

Macroporous silicon dead end pores on bulk silicon wafer (360006-W07)

Etching

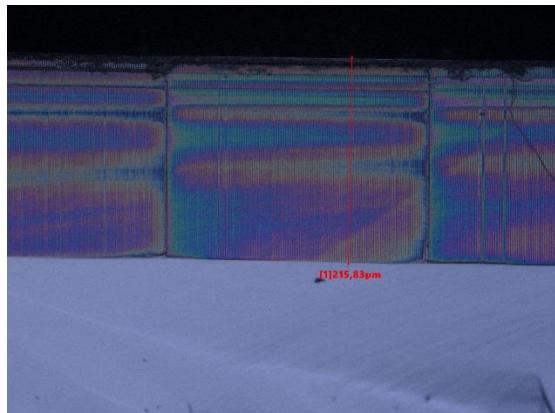
Size:	6 inch
Pitch:	1.5 µm square
Pore length:	215 µm
Pore diameter:	0.8-1.0 µm

Postprocessing

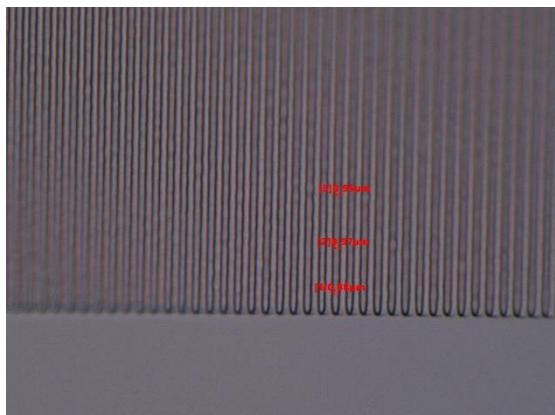
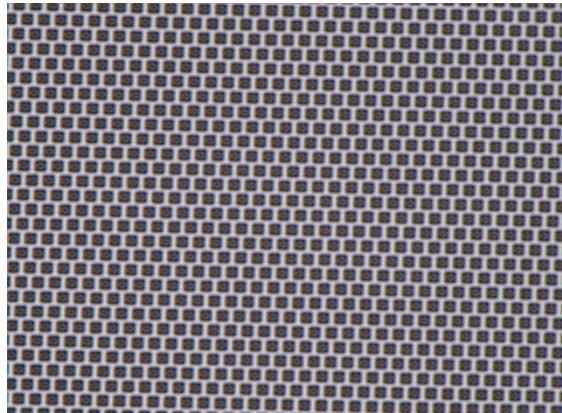
- Laserdicing

Measurements

Side views



Front side view



Please note: The wafer surface is prestructured with pyramidal pits prior to the photoelectrochemical pore formation process. Thus, optical microscopy from the front side does not show the real pore diameter.